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Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet	1	of	1
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Complete if Kn wn

Application Number	To Be Assigned
Filing Date	Herewith
First Named Inventor	Eric Prophet
Group Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned
Attorney Docket Number	269/132

jc997 U.S. PTO

10/072656



U.S. PATENT DOCUMENTS

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OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

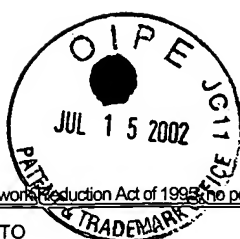
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
Loke	AB	NIELS TAS, TONNY SONNENBERG, HENRI JANSEN, ROB LEGTENBERG, MIKO ELWENSPOEK, <i>Stiction in Surface Micromachining</i> , 1996, Pages 385-397, IOP Publishing Ltd., United Kingdom	
Loke	AC	TAKESHI ABE, MICHAEL L. REED, <i>Control of Liquid Bridging Induced Stiction of Micromechanical Structures</i> , 1996, Pages 213-217, IOP Publishing Ltd., United Kingdom	

Examiner Signature	<i>Loke</i>	Date Considered	<i>4/25/03</i>
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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PTO/SB/08A (10-01)

Approved for use through 10/31/2002. OMB 0651-0031

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**INFORMATION DISCLOSURE
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(use as many sheets as necessary)

Sheet 1

of

2

Complete if Known

Application Number	10/072,656
Filing Date	February 7, 2002
First Named Inventor	Eric Prophet
Group Art Unit	2811
Examiner Name	Not Yet Assigned
Attorney Docket Number	269/132

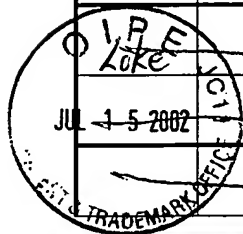
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Examiner Initials *	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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Loke		US-5,079,657	01/07/1992	Aronoff et al.	
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TECHNOLOGY CENTER 2800**OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS**

Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
Loke		ABE, Takeshi et al., Control of Liquid Bridging Induced Stiction of Micromechanical Structures, J.Micromech. Microeng. 6 (1996) 213-217	
		AL MANZA-WORKMAN, A.M., et al., Water Dispersible Silanes for Wettability Modification of Polysilicon for Stiction Reduction in Silicon Based Micro-Electromechanical Structures	
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		MABOUDIAN, R. et al., Self-Assembled Monolayers as Anti-Stiction Coatings for MEMS: Characteristics and Recent Developments	
		MABOUDIAN, R., Critical Review: Adhesion in Surface Micromechanical Structures, J. Vac. Sci. Technol. B 15(1), Jan/Feb 1997, pp 1-20	
		MASTRANGELO, C.H., Suppression of Stiction in MEMS	

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		TAS, N. et al., Side-Wall Spacers for Stiction Reduction in Surface Micromachined Mechanisms	
		TAS, Niels et al., Stiction in Surface Micromachining, 1996, Pages 385-397, IOP Publishing Ltd., United Kingdom	
		YANG, Lung-Jieh et al., Photo-Patternable Gelatin as Protection Layers in Surface Micromachining	
		YAO, Tze-Jung et al., BrF3 Dry Release Technology for Large-Freestanding Polyene MEMS	



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